EXPERIENCE · PRECISION · PERFORMANCE



COMING TO IMAPS 2016....

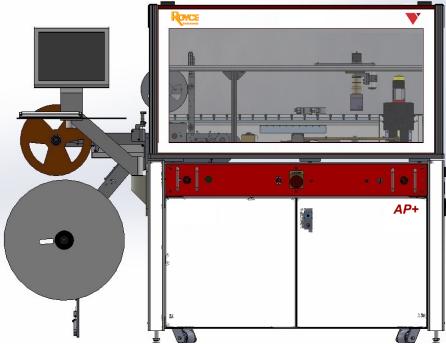


AP+ configured for pick from wafer, place to carrier tape

Royce Instruments AP+

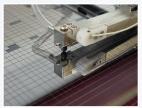
Combining over 30 years of experience, Royce's fragile die pick capability, and V-TEK's latest small die taping technology

A new automated die sorter to handle the output mediums your process requires (carrier tape, waffle pack, Gel-Pak, JEDEC tray, film frame, grip ring, and custom trays). The AP+ can pick die from wafer, waffle pack, Gel-Pak, JEDEC tray, or custom tray using an input map, perform an optional 180 degree die flip, and place to output, while maintaining input to output traceability at the die level. With its multi-project (pizza map or reticle mask) wafer mapping capability and quick-change fixtures and tooling, this system gives you the highest level of flexibility while maintaining fast change over between processes to support low to medium volume, high mix environments.



Specifications:

Die Size Range	0.2 mm sq to > 25 mm sq for tray placement, 0.5 um sq to approx. 17 mm sq for tape placement
Die Input	Film frames or wafer rings, in all current designs, for wafers up to 300 mm diameter Waffle packs, Gel-Paks, JEDEC trays, and custom trays
Pick-up Technology	Surface or top edge contact vacuum tips (rubber, Vespel, tungsten carbide, elastomer) Optional non-surface contact Vespel edge grip
Die Output	Carrier tape (8 mm to 24 mm tape width, heat seal or pressure seal), waffle packs and Gel-Paks (2 inch or 4 inch), JEDEC trays, film frames, wafer rings, or custom. Changeover time between carrier tape placement and tray placement is less than 2 hours.
Placement	± 12.5 micron placement repeatability
Die Sort Modes	Wafer mapping (SEMI E142, Electroglas 40x0, August Simplified INF, SEMI G85-0703, SEMI G85-1101, custom, create your own), ink dot recognition, pick all die
Throughput	Application dependent, 1.3 seconds minimum time per cycle
Options	Die Inverter, Post-Place Vision Inspection of Die in Carrier Tape
Dimensions	2058 mm (81 in) long x 1016 mm (40 in) deep x 2235 mm (88 in) high (with cover open)
Facilities Requirements	Compressed Air at 275 kPa to 410 kPa (40 to 60 psi), Vacuum at -65 kPa (20 in Hg), Electrical at 120-240 VAC \pm 10%
Placement Die Sort Modes Throughput Options Dimensions Facilities	inch or 4 inch), JEDEC trays, film frames, wafer rings, or custom. Changeover time between carrier tape placement and tray placement is less than 2 hours. ± 12.5 micron placement repeatability Wafer mapping (SEMI E142, Electroglas 40x0, August Simplified INF, SEMI G85-0703, SEMI G85-1101, custom, create your own), ink dot recognition, pick all die Application dependent, 1.3 seconds minimum time per cycle Die Inverter, Post-Place Vision Inspection of Die in Carrier Tape 2058 mm (81 in) long x 1016 mm (40 in) deep x 2235 mm (88 in) high (with cover open) Compressed Air at 275 kPa to 410 kPa (40 to 60 psi), Vacuum at –65 kPa (20 in Hg),







Contact Us

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Proudly manufacturing in the U.S.A since 1983

